

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.	:	10/595,660	Confirmation No. 4264
Applicant	:	Yuichiro Shindo	
371(c) Date	:	May 3, 2005	
Art Unit	:		
Examiner	:		
Customer No.	:	00270	
Title	:	HIGH PURITY HAFNIUM, TARGET AND THIN FILM COMPRISING SAID HIGH PURITY HAFNIUM, AND METHOD FOR PRODUCING HIGH PURITY HAFNIUM	

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

In compliance with their duty to disclose under 37 CFR §1.56(a), Applicants and their attorneys enclose a form PTO-1449 and copies of the foreign and other documents listed therein.

The listed references were cited in the International Search Report for International Application No. PCT/JP04/15777, or are discussed on page 2 of the present application, or are related U.S. or European patent documents. Co-pending U.S. Patent Application No. 10/565,767 filed on January 24, 2006 is cited with respect to double patenting issues only.

The Examiner is respectfully requested to consider the cited documents and to make the same of record in the file of the present application.

In the event that a fee for the Information Disclosure Statement is required, please charge the fee to our Deposit Account No. 08-3040.

Respectfully submitted,
HOWSON AND HOWSON
Attorneys for Applicant

By /William Bak/
William Bak
Reg. No. 37,277
501 Office Center Drive
Suite 210
Fort Washington, PA 19034
(215) 540-9216

Form PTO-1449 U.S. Patent and Trademark Office INFORMATION DISCLOSURE STATEMENT	Atty. Docket No. OGOSH53USA	Serial No. 10/595,660
	Applicant: Yuichiro Shindo	
	371 (c) Date: May 3, 2006	Group Art Unit:

U.S. PATENT DOCUMENTS

Examiner Initial		Document No.	Date	Name	Class	Subclass
		6,861,030 B2	3/2005	Shindo	420	422
		6,737,030 B2	5/2004	Sommers et al.	423	70
		4,897,116	1/1990	Scheel	75	84.5
		4,668,287	5/1987	Kwon	75	84.5
		4,637,831	1/1987	Stoltz et al.	75	84.5

FOREIGN PATENT DOCUMENTS

Examiner Initial		Document No.	Date	Country	Translation Yes	No
		JP 04-358030	12/1992	Japan	Abstract only	X
		JP 07-316681	12/1995	Japan	Abstract only	X
		JP 2003-193150	7/2003	Japan	Abstract only	X
		JP 04-099829	3/1992	Japan	Abstract only	X
		JP 2000-345252	6/1999	Japan	Abstract only	X
		EP 0154448 A2	9/1985	European		
		EP 0134643 A2	3/1985	European		

Other Documents (including Author, Title, Date, Pertinent Pages, Etc.)

		Esp@cenet, One Page English Abstract of JP 10-204554, August 1998
		Esp@cenet, One Page English Abstract of JP 61-242993, October 1986
		Co-pending U.S. Patent Application No. 10/565,767 filed January 24, 2006
Examiner		Date Considered

*Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.